



Session Title:	[MF1] Frontier Metrology and Modeling I
Session Date:	November 20 (Mon.), 2023
Session Time:	13:00-14:45
Session Room:	Room F (Sicily Room, 1F)
Session Chair:	Prof. Tae-Hun Shim (Hanyang Univ., Korea)

[MF1-1] [Plenary]

13:00-13:45

Patterning and Metrology Challenges in EUV Lithography

Victor M. Blanco Carballo (imec, Belgium)

[MF1-2]

13:45-14:15

Advancing Semiconductor Research with AFM: High-Resolution Imaging, Precise Measurements, and Failure Analysis

Seong Oh Kim, Yun Kyung Lee, Seung Yun Seong, and Dong Chun Lee (Park Systems, Korea)

[MF1-3] [Invited]

14:15-14:45

Adaptive Optics for Optical Metrology & Inspection

Jun Ho Lee, Ji Won Park, Jun Sung Lee, Ji Yong Joo (Kongju Nat'l Univ., Korea), and Oh-Hyung Kwon (NEXTIN, Korea)